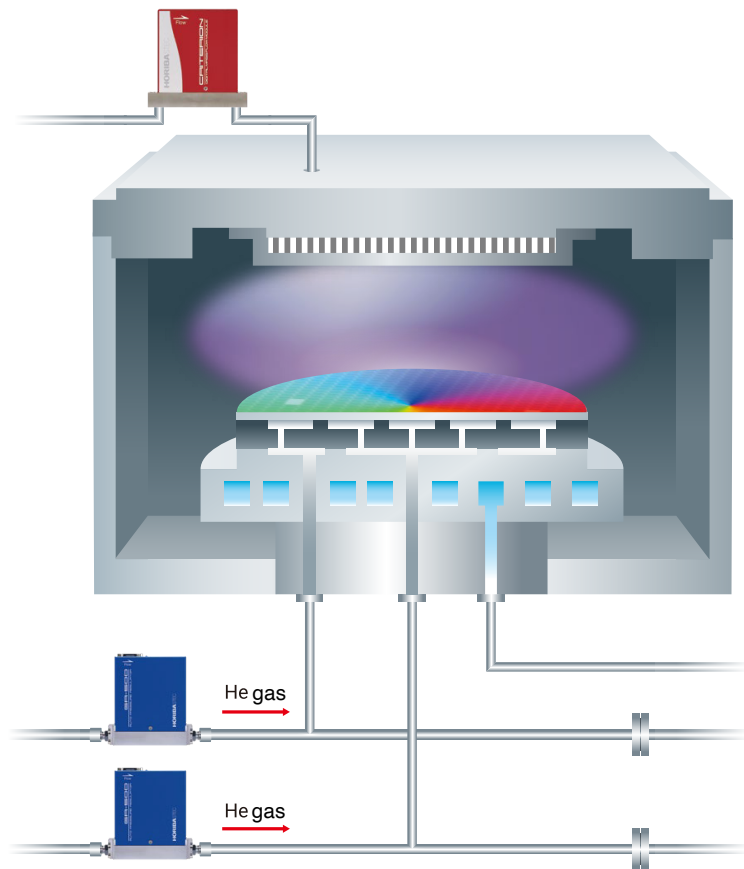


>>> Fluid Control

Fluid Control Technology



Control backside wafer pressure

Control system for back wafer pressure GR-500

- Add 10, 20, and 50 Torr to the 100 Torr pressure of the conventional model for precise pressure control
- Monitoring of gas flow on the back surface of the wafer by the mount



Compact gas panel

Ultra thin differential pressure type DZ-100

- Contributes to reducing footprint
- Compact gas line expansion
- Light weight increases gas-pox installation freedom

1.125 inch integrated gas supply $\xrightarrow{\text{foot print approx. 40\%* reduction}}$ 10 mm Integrated gas supply

*16Line Etch Assumption

